

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: TAKAAKI SHIOTA, YOSHINOBU NAKADA

Application No.:

Confirmation

No:

Filed: November 13, 2003

Group No.:

Examiner

For: SILICON WAFER AND MANUFACTURING METHOD THEREOF

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

APPLICATION DATA SHEET  
37 C.F.R. § 1.76

BIBLIOGRAPHIC DATA

**1. Applicant information**

First applicant: TAKAAKI SHIOTA  
Citizenship: JAPAN  
Residence: Tokyo, Japan

Second applicant: YOSHINOBU NAKADA  
Citizenship: JAPAN  
Residence: Tokyo, Japan

**2. Correspondence information**

Correspondence for this application should be addressed as follows:

Customer No.: 00909

**3. Application information**

Title of Invention: SILICON WAFER AND MANUFACTURING METHOD THEREOF

Docket number assigned to this application: 061063-0306825

Suggested Classification: Class:  
Subclass:  
Technology Center to which subject matter is assigned:

Total number of drawing sheets: 4

Type of application:

**Utility**

Application is to be published. Suggested drawing figure for publication:

Secrecy order under § 5.2:

This application does not disclose subject matter of an application which is under a secrecy order pursuant to § 5.2.

**4. Representative information**

The following have a power of attorney or authorization of agent in this application:

Customer No.: 00909

**5. Foreign priority information**

Foreign priority is claimed for this application as follows:

Country: JAPAN

Application No.: 2002-336690

Filing Date: November 20, 2002

Status: pending

**6. Assignee information**

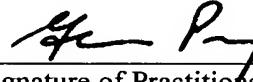
The assignee(s) of this application is/are:

Sumitomo Mitsubishi Silicon Corporation  
2-1, Shibaura 1-chome, Minato-ku  
Tokyo,  
JAPAN

Extent of interest of assignee in application: 100%

Date: 11-13-2003

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